



Docket No.: 57810-077

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Yasuhiko NOMURA, et al:

Serial No.: 10/663,707

Filed: September 17, 2003

For: NITRIDE-BASED SEMICONDUCTOR LASER DEVICE

: Customer Number: 20277
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: Confirmation Number: 3966
:
: Group Art Unit: 2828
:
: Examiner:
:

INFORMATION DISCLOSURE STATEMENT

Mail Stop IDS
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

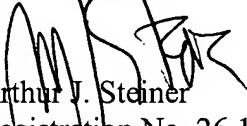
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10/663,707

Please charge any shortage in fees due in connection with the filing of this paper, including extension of time fees, to Deposit Account 500417 and please credit any excess fees to such deposit account.

Respectfully submitted,

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INFORMATION DISCLOSURE CITATION IN AN APPLICATION

 ATTY. DOCKET NO.
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 SERIAL NO.
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 APPLICANT
Yasuhiko NOMURA, et al.

 FILING DATE
September 17, 2003

 GROUP
2828

(PTO-1449)

U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	CITE NO.	Document Number Number-Kind Codez (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		US			
		US			
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FOREIGN PATENT DOCUMENTS

EXAMINER'S INITIALS	CITE NO.	Foreign Patent Document Country Codes -Number 4 -Kind Codes (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines Where Relevant Figures Appear	Translation	
						Yes	No
		JP 2002-124737	04/26/2002	SANYO ELECTRIC CO LTD		JAPAN (w/English Abstract)	
		JP 2002-299768	10/11/2002	MATSUSHITA ELECTRIC IND CO LTD		JAPAN (w/English Abstract)	
		JP 2001-57461	02/27/2001	NICHIA CHEM IND LTD		JAPAN (w/English Abstract)	
		JP 11-340580	12/10/1999	FUJITSU LTD		JAPAN (w/English Abstract)	
		JP 10-294529	11/4/1998	TOSHIBA CORP.		JAPAN (w/English Abstract)	

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

EXAMINER'S INITIALS	CITE NO.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	
		Nishinaga Tatau, "Hetero-epitaxy with Large Lattice Mismatch and Microchannel Epitaxy of Compound Semiconductor." Department of Electronic Engineering, Graduate School of Engineering, Volume 21, No. 6, pp. 320-325, 2000	
		H. Amano, et al. "Metalorganic vapor phase epitaxial growth of a high quality GaN film using an AlN buffer layer." Appl. Phys. Lett., Vol. 48, No. 5, 3 February 1986. pp. 353-355	

EXAMINER

DATE CONSIDERED

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

1 Applicant's unique citation designation number (optional). 2 Applicant is to place a check mark here if English language Translation is attached.